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APPLICATION NO. FILING		ATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.	
10/785,005	10/785,005 02/25/2004		Shigeru Fujita	SON-2612/DIV	9742	
23353	7590 11/28/2005			EXAM	EXAMINER	
	SHMAN & GR	LE, TH	LE, THAO X			
LION BUIL 1233 20TH	DING STREET N.W., S	SUITE 501	ART UNIT	PAPER NUMBER		
WASHING	TON, DC 2003	66	2814			
				DATE MAILED: 11/28/2005	5	

Please find below and/or attached an Office communication concerning this application or proceeding.

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		Application No.	Applicant(s)	()			
Office Action Summary		10/785,005	FUJITA, SHIGERU				
		Examiner	Art Unit				
		Thao X. Le	2814				
Period fo	The MAILING DATE of this communication a or Reply	opears on the cover shee	t with the correspondence add	ress			
THE - Exte after - If the - If NC - Failu Any	ORTENED STATUTORY PERIOD FOR REP MAILING DATE OF THIS COMMUNICATION nsions of time may be available under the provisions of 37 CFR 1 SIX (6) MONTHS from the mailing date of this communication, or period for reply specified above is less than thirty (30) days, a representation of the present of the period for reply is specified above, the maximum statutory perion reply within the set or extended period for reply will, by staturely received by the Office later than three months after the mailed patent term adjustment. See 37 CFR 1.704(b).	l.  1.136(a). In no event, however, ma  2.136(a). In no event, however, how	ly a reply be timely filed  f thirty (30) days will be considered timely.  MONTHS from the mailing date of this content is a second to the content is a seco	nmunication.			
Status							
1)⊠	Responsive to communication(s) filed on 27	October 2005.					
2a)⊠	This action is <b>FINAL</b> . 2b) This action is non-final.						
3)□	Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under <i>Ex parte Quayle</i> , 1935 C.D. 11, 453 O.G. 213.						
Disposit	ion of Claims						
5)□ 6)⊠ 7)□	Claim(s) 1-5 and 13-16 is/are pending in the 4a) Of the above claim(s) is/are withdra Claim(s) is/are allowed.  Claim(s) 1-5 and 13-16 is/are rejected.  Claim(s) is/are objected to.  Claim(s) are subject to restriction and	wn from consideration.					
Applicat	ion Papers						
, —	The specification is objected to by the Exami						
10)	10) The drawing(s) filed on is/are: a) accepted or b) objected to by the Examiner.						
	Applicant may not request that any objection to the			-			
11)	Replacement drawing sheet(s) including the correct The oath or declaration is objected to by the						
Priority (	under 35 U.S.C. § 119						
a)	Acknowledgment is made of a claim for foreign All b) Some * c) None of:  1. Certified copies of the priority docume 2. Certified copies of the priority docume 3. Copies of the certified copies of the priority docume application from the International Bures See the attached detailed Office action for a life	nts have been received. nts have been received iority documents have be eau (PCT Rule 17.2(a)).	in Application No een received in this National S	Stage			
Attachmer	nt(s) ce of References Cited (PTO-892)	4) 🗍 Intervi	iew Summary (PTO-413)				
2) Notion Notion Notion Notion	ce of References Cited (FTO-652) ce of Draftsperson's Patent Drawing Review (PTO-948) rmation Disclosure Statement(s) (PTO-1449 or PTO/SB/0 er No(s)/Mail Date	Paper	No(s)/Mail Date e of Informal Patent Application (PTO	-152)			

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### **DETAILED ACTION**

### Claim Rejections - 35 USC § 102

- 1. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:
  - (e) the invention was described in (1) an application for patent, published under section 122(b), by another filed in the United States before the invention by the applicant for patent or (2) a patent granted on an application for patent by another filed in the United States before the invention by the applicant for patent, except that an international application filed under the treaty defined in section 351(a) shall have the effects for purposes of this subsection of an application filed in the United States only if the international application designated the United States and was published under Article 21(2) of such treaty in the English language.
- 2. Claims 1-4, 13-15 are rejected under 35 U.S.C. 102(e) as being anticipated by US Pub 2002/0190302 to Bojarczuk, Jr.

Regarding claim 1, Bojarczuk discloses a semiconductor device fig. 1 and 4 comprising: a semiconductor substrate 210 [0031], a high dielectric-constant film 220 [0016] on the semiconductor substrate 210, and a nitride layer 430 [0036] & [0038] on the high-dielectric-constant film 220, fig. 6, wherein the high dielectric constant film 220 is selected from film comprised of enhanced dielectric material including Al<sub>2</sub>O<sub>3</sub> and silicate [[0016] derided from said enhanced dielectric material, and film having multiple-layered structure including at least two layers (220/220), fig. 4, of said silicate film [0016].

Regarding claims 2-4, 14-15, Bojarczuk discloses the semiconductor device further comprises a p-type impurity-contained layer 240 [0009] on the nitride layer 430, fig. 4, wherein the nitride layer 430 is formed by introducing nitrogen in to the top

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surface portion of the high-dielectric-constant film 220 [0018], wherein the semiconductor substrate 210 is a silicon substrate [0031].

Regarding claim 13, Bojarczuk discloses a semiconductor device in fig. 1 and 4 comprising: a semiconductor substrate 210, a gate insulating film 220 on a semiconductor substrate 210, and a gate electrode 240 formed on the gate insulating film 220 and including at least a p-type impurity layer [0009] and [0042], wherein the gate insulating film includes a high-dielectric-constant film 220 and a nitride layer 430, fig. 4, on the high-dielectric-constant film 220, wherein the high dielectric constant film 220 is selected from film comprised of enhanced dielectric material of films including Al<sub>2</sub>O<sub>3</sub>, silicate [0016] film derived from said enhanced dielectric material, and film having multiple-layer structure of at least two layers of said silicate film [0016].

But Jeon does not expressly disclose a gate electrode 108

However, Ramkumar discloses a semiconductor device wherein

polysilicon gate layer is being doped with boron to form P-type gate, column 1 line 27-30. At the time the invention was made; it would have been obvious to one of ordinary skill in the art to use the p-type polysilicon gate teaching of Ramkumar with Jeon's layer 108, because it would have created a p-type gate MOSFETS.

## Claim Rejections - 35 USC § 103

3. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

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(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

4. Claims 5 and 16 are rejected under 35 U.S.C. 103(a) as being unpatentable over US Pub 2002/0190302 to Bojarczuk, Jr.

Regarding claims 5 and 16, Bojarczuk discloses the semiconductor device wherein the p-type impurity-contained layer 240 [0009].

But Bojarczuk does not expressly disclose the boron-contained silicon layer. At the time the invention was made; it would have been obvious to one of ordinary skill in the art to use boron to created p-type silicon, because such boron doping to create a p-type layer is conventional in the art, see Ramkumar in column 1 line 27-30.

### Response to Arguments

5. Applicant's arguments filed 27 Oct. 2005 have been fully considered but they are not persuasive. The Applicant argues that Bojarczuk fails to disclose the high-K layer 220 includes Al<sub>2</sub>O<sub>3</sub> and the barrier 230 is an insulating layer selected from, among others, Al<sub>2</sub>O<sub>3</sub>. This is not persuasive because Bojarczuk clearly show in fig. 1 step 120 'apply high-K dielectric' or layer 220 in fig. 2-4. The list of high k dielectric includes Al<sub>2</sub>O<sub>3</sub> or silicates thereof in [0008] and [0016], while the barrier layer 230/330/430 acts as a diffusion barrier [0034] that comprises silicon nitride [0038].

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#### Conclusion

6. **THIS ACTION IS MADE FINAL.** Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will the statutory period for reply expire later than SIX MONTHS from the mailing date of this final action.

7. Any inquiry concerning this communication or earlier communications from the Examiner should be directed to Thao X. Le whose telephone number is (571) 272-1708. The examiner can normally be reached on M-F from 8:00 AM - 4:30 PM.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Wael M. Fahmy can be reached on (571) 272 -1705. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

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Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Thao X. Le 18 November 2005

PRIMARY EXAMINER